Next Committee Meeting
FPD Materials & Components Japan TC Chapter:
SEMI Japan Standards Summer 2015 Meetings
Monday, July 27, 2015, 15:00-17:00
SEMI Japan, Tokyo, Japan

FPD Metrology Japan TC Chapter:
SEMI Japan Standards Fall 2015 Meetings
October, 2015 (TBD)
SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees
Co-Chairs of FPD M&C Committee: Tadahiro Furukawa (Yamagata University), Yoshi Shibahara (Fujifilm)
Co-Chairs of FPD Metrology Committee: Ryoichi Watanabe (Japan Display), Akira Kawaguchi (Otsuka Electronics)
SEMI Staff: Naoko Tejima (SEMI Japan)

<table>
<thead>
<tr>
<th>Company</th>
<th>Last</th>
<th>First</th>
<th>Company</th>
<th>Last</th>
<th>First</th>
</tr>
</thead>
<tbody>
<tr>
<td>Yamagata University</td>
<td>Furukawa</td>
<td>Tadahiro</td>
<td>Fujifilm</td>
<td>Sato</td>
<td>Tadanobu</td>
</tr>
<tr>
<td>Teijin</td>
<td>Itoh</td>
<td>Haruhiko</td>
<td>Fujifilm</td>
<td>Shibahara</td>
<td>Yoshi</td>
</tr>
<tr>
<td>Otsuka Electronics</td>
<td>Kawaguchi</td>
<td>Akira</td>
<td>Japan Display</td>
<td>Watanabe</td>
<td>Ryoichi</td>
</tr>
<tr>
<td>HOYA</td>
<td>Nitobe</td>
<td>Kaname</td>
<td>ITRI</td>
<td>Wen</td>
<td>Chao-Hua</td>
</tr>
<tr>
<td>Nitto Denko</td>
<td>Kobayashi</td>
<td>Shigeo</td>
<td>Japan Business Society</td>
<td>Yamagishi</td>
<td>Naomichi</td>
</tr>
<tr>
<td>Meiji University</td>
<td>Nagai</td>
<td>Kazukiyo</td>
<td>SEMI Japan</td>
<td>Tejima</td>
<td>Naoko</td>
</tr>
<tr>
<td>Konica Minolta.</td>
<td>Ochi</td>
<td>Keizo</td>
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</tr>
</tbody>
</table>

* alphabetical order by last name

Table 2 Leadership Changes
FPD Materials & Components Japan TC Chapter
None.

FPD Metrology Japan TC Chapter
None.

Table 3 Ballot Results
FPD Materials & Components Japan TC Chapter
None.

FPD Metrology Japan TC Chapter
None.
### Table 4 Authorized Ballots
**FPD Materials & Components Japan TC Chapter**

<table>
<thead>
<tr>
<th>Document #</th>
<th>When</th>
<th>SC/TF/WG</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>5555</td>
<td>Cycle 5, 2015</td>
<td>Polarizing Film TF</td>
<td>Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components</td>
</tr>
</tbody>
</table>

**FPD Metrology Japan TC Chapter**

None.

### Table 5 Authorized Activities
**FPD Materials & Components Japan TC Chapter**

<table>
<thead>
<tr>
<th>Document #</th>
<th>Type</th>
<th>SC/TF/WG</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>5555</td>
<td>Revised SNARF</td>
<td>Polarizing Film TF</td>
<td>Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components</td>
</tr>
</tbody>
</table>

**FPD Metrology Japan TC Chapter**

None.

### Table 6 New Action Items
**FPD M&C Japan TC Chapter**

<table>
<thead>
<tr>
<th>Item #</th>
<th>Assigned to</th>
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</tr>
</thead>
<tbody>
<tr>
<td>FPD M&amp;C 150206-03</td>
<td>SEMI Staff</td>
<td>To forward adjudication result of Doc.#5796 to the ISC A&amp;R Subcommittee for procedural review.</td>
</tr>
<tr>
<td>FPD M&amp;C 150206-04</td>
<td>SEMI Staff</td>
<td>To forward adjudication result of Doc.#5797 to the ISC A&amp;R Subcommittee for procedural review.</td>
</tr>
<tr>
<td>FPD M&amp;C 150206-05</td>
<td>SEMI Staff</td>
<td>To forward adjudication result of Doc.#5798 to the ISC A&amp;R Subcommittee for procedural review.</td>
</tr>
<tr>
<td>FPD M&amp;C 150206-06</td>
<td>SEMI Staff</td>
<td>To forward adjudication result of Doc.#5799 to the ISC A&amp;R Subcommittee for procedural review.</td>
</tr>
<tr>
<td>FPD M&amp;C 150410-01 Polarizing Film TF</td>
<td>To submit the ballot of SEMI D50 (#5555) for Cycle 5, 2015</td>
<td></td>
</tr>
<tr>
<td>FPD M&amp;C 150410-02 Flexible Display TF</td>
<td>To check whether there are the existences of the patented technology in the Doc. 5551, and to discuss a way not to include the patented technologies.</td>
<td></td>
</tr>
<tr>
<td>FPD M&amp;C 141030-06 Flexible Display TF</td>
<td>To submit the new SNARF of Doc. #5551 3-week before the next Japan TC Chapter meeting (by July 6).</td>
<td></td>
</tr>
</tbody>
</table>

**FPD Metrology Japan TC Chapter**

<table>
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</thead>
<tbody>
<tr>
<td>FPD Metrology 150410-01</td>
<td>SEMI Staff</td>
<td>To contact the co-leaders of D31 Revision TF (Kose Tanahashi and Masao Kochi) and ask their intention.</td>
</tr>
</tbody>
</table>
1 Welcome, Reminders, and Introductions
Tadahiro Furukawa, committee co-chair, called the meeting to order at 14:00. Self-introductions were made followed by the agenda review.

2 Required Meeting Elements
The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed by SEMI staff, Naoko Tejima.

3 SEMI Staff Report

Follow-up revisions of Regulations and Procedure Manual were published on 27 March, 2015 for use in NA Spring Standard meetings and it was briefly introduced by Junko Collins.

Attachment: 01_SEMI_Staff_Report_150410
Attachment: 02_ISC_Subcommittee_on_the_Regulations_150410

4 Liaison Reports
4.1 Korea FPD Committee Report
Naoko Tejima reported for the Korea FPD Metrology Committee. This report included Leadership, Organization Chart, Meeting Information, Major Updates, Subcommittee /TF/WG Updates” and Contact Information.

Attachment: 03_KR_FPD_Liaison_Report_150410

4.2 Taiwan FPD Committee Report
Naoko Tejima reported for the Taiwan FPD Committee. This report included FPD Metrology Standard Committee Organization Chart, FPD Standard Committee Highlights, FPD Committee Meeting Information and Contact Information.

Attachment: 04_TW_FPD_Liaison_Report_150410

5 Review of Previous Meeting Minutes
The committee reviewed the minutes of the previous meeting held on February 6, 2015.

Motion: To approve the minutes of the previous meeting as written.
By / 2nd: Yoshi Shibahara (Fujifilm) / Ryoichi Watanabe (Japan Display)
Discussion: None
Vote: 10 in favor and 0 opposed. Motion passed.
Attachment: 05_JA_FPD_M&C_Previous_Mtg_Minutes_150410

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attachment: 01_SEMI_Staff_Report_150410
attachment: 02_ISC_Subcommittee_on_the_Regulations_150410
attachment: 03_KR_FPD_Liaison_Report_150410
attachment: 04_TW_FPD_Liaison_Report_150410
attachment: 05_JA_FPD_M&C_Previous_Mtg_Minutes_150410
6 Task Force Reports

6.1 Polarizing Film Task Force
Yoshi Shibahara reported for the Polarizing Film Task Force. The Task Force met earlier in the day. Of note:

- Working for Doc. #5555, Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film.
- Revise SNARF to expand the scope of D50 from the polarizing film to FPD Components.

Motion: To approve the revised SNARF for “Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components” to expand the scope.

By / 2nd: Yoshi Shibahara (Fujifilm) / Shigeo Kobayashi (Nitto Denko)
Discussion: None.
Vote: 11 in favor and 0 opposed. Motion passed.

Motion: To submit the Doc. 5555, “Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components” for Cycle 5, 2015.

By / 2nd: Yoshi Shibahara (Fujifilm) / Shigeo Kobayashi (Nitto Denko)
Discussion: None.
Vote: 11 in favor and 0 opposed. Motion passed.

Action Item: Polarizing Film Task Force to submit the ballot of SEMI D50 (#5555) for Cycle 5, 2015

Shigeo Kobayashi reported that TF had been discussing about Specification of dimensions of polarizer and related materials especially for non-rectangular shape as new business.

Attachment: 06_Polarizing_Film_TF_Report_150410

6.2 Flexible Display Task Force
Haruhiko Itoh reported on progress for the Flexible Display Task Force. The Task Force met earlier in the day. Of note:

- There is possibility to include the Patented Technologies in the Doc. #5551. TF will check it again and discuss a way not to include the patented technologies.
- If it is known that patented technology is intended to be included in the proposed Document(s), then the proposer shall inform Standards Staff. Standards staff shall then request and obtain a letter of intent (LOI) from the holder(s) of the patented technology (hereinafter called patent holder(s)). (Regulation 16.2.1)

Action Item: Flexible Display Task Force to check whether there are the existences of the patented technology in the Doc. 5551, and to discuss a way not to include the patented technologies.

Action Item: Flexible Display Task Force to submit the new SNARF of Doc. #5551 3-week before the next Japan TC Chapter meeting (by July 6).

6.3 Color Filter Task Force
Tadahiro Furukawa reported for the Color Filter Task Force that there were no particular things should be reported.

6.4 FPD Mask Task Force
Kaname Nitobe reported for the FPD Mask Task Force that there were no particular things should be reported.
7 Old Business

7.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 7 Previous Meeting Actions Items

<table>
<thead>
<tr>
<th>Item #</th>
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<tbody>
<tr>
<td>FPD M&amp;C 150206-01</td>
<td>SEMI Staff</td>
<td>To correct start time of the next FPD Metrology Japan TC Chapter meeting to 14:00 of the previous meeting minutes. … Close</td>
</tr>
<tr>
<td>FPD M&amp;C 150206-02</td>
<td>SEMI Staff</td>
<td>To correct FPD M&amp;C 140418-01 in Table 7 Previous Meeting Action Items to “to contact Backlight Task Force co-leaders” of the previous meeting minutes. … Close</td>
</tr>
<tr>
<td>FPD M&amp;C 150206-03</td>
<td>SEMI Staff</td>
<td>To forward adjudication result of Doc.#5796 to the ISC A&amp;R Subcommittee for procedural review. … Open</td>
</tr>
<tr>
<td>FPD M&amp;C 150206-04</td>
<td>SEMI Staff</td>
<td>To forward adjudication result of Doc.#5797 to the ISC A&amp;R Subcommittee for procedural review. … Open</td>
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<tr>
<td>FPD M&amp;C 150206-05</td>
<td>SEMI Staff</td>
<td>To forward adjudication result of Doc.#5798 to the ISC A&amp;R Subcommittee for procedural review. … Open</td>
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<tr>
<td>FPD M&amp;C 150206-06</td>
<td>SEMI Staff</td>
<td>To forward adjudication result of Doc.#5799 to the ISC A&amp;R Subcommittee for procedural review. … Open</td>
</tr>
<tr>
<td>FPD M&amp;C 150206-07</td>
<td>Polarizing Film Task Force</td>
<td>To send the revised SNRAF of Doc. #5555 to SEMI until March 15 for 2 weeks review by TC Members. … Close</td>
</tr>
<tr>
<td>FPD M&amp;C 150206-08</td>
<td>SEMI Staff</td>
<td>To send the revised SNRAF of Doc. #5555 to Global TC Members to review for 2 weeks. … Close</td>
</tr>
</tbody>
</table>

8 New Business

None.

[Japan FPD Metrology Committee Part]

9 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on April 18, 2014.

Motion: To approve the minutes of the previous meeting as written.

By / 2nd: Akira Kawaguchi (Otsuka Electronics) / Haruhiko Itoh (Teijin)

Discussion: None

Vote: 11 in favor and 0 opposed. Motion passed.

Attachment: 07_JA_FPD_M&C_&_Metrology_Previous_Mtg_Minutes_150410

10 Task Force Reports

10.1 D31 Revision Task Force

Keizo Ochi reported on progress for the D31 Revision Task Force that there were no particular things should be reported.

11 Old Business

11.1 Previous Meeting Action Items

None.
12 New Business

None.

[Common Part 2]

13 New Business of FPD Coordination Group

FPD Coordination Group meeting will be held on May 29, and will discuss the FPD Workshop should be held or not.

14 Action Item Review

14.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

15 Next Meeting and Adjournment

The next meeting of the FPD Materials & Components Japan TC Chapter is scheduled for Monday, July 27, 2015, 15:00-17:00, SEMI Japan, Tokyo, Japan

The next meeting of the FPD Metrology Japan TC Chapter is scheduled for October (TBD).
Table 8 Index of Available Attachments #1

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<th>#</th>
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</tr>
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<tr>
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<td>SEMI_Staff_Report_150410</td>
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</tr>
<tr>
<td>6</td>
<td>Polarizing_Film_TF_Report_150410</td>
</tr>
<tr>
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<td>JA_FPD_M+C_Metrology_Previous_Mtg_Minutes_150410</td>
</tr>
</tbody>
</table>

#1 Due to file size and delivery issues, attachments must be downloaded separately. A zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.